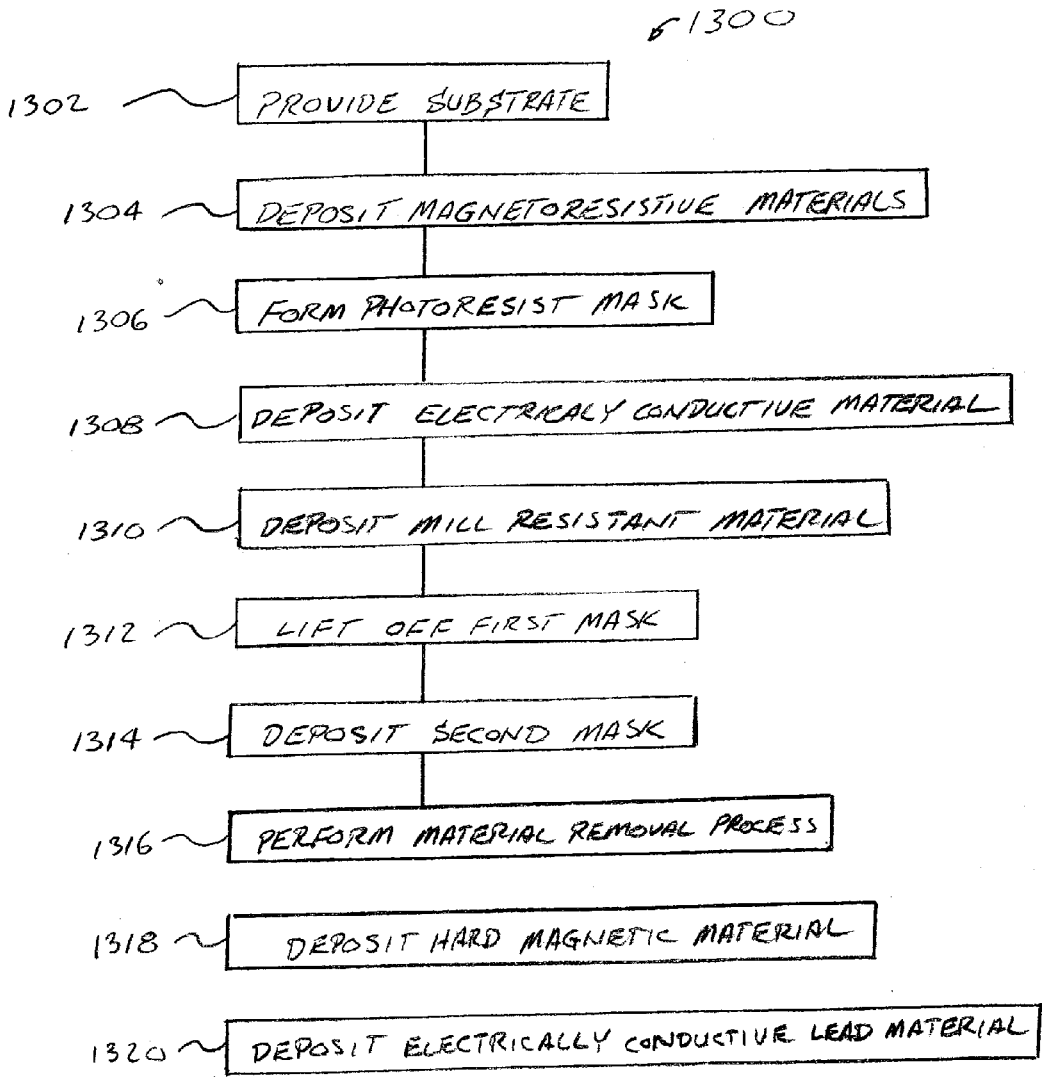
1300
1302
PROVIDE SUBSTRATE
1304
DEPOSIT MAGNETORESISTIVE MATERIALS
1306
FORM PHOTORESIST MASK
1308
DEPOSIT ELECTRICALY CONDUCTIVE MATERIAL
1310
DEPOSIT MILL RESISTANT MATERIAL
1312
LIFT OFF FIRST MASK
1314
DEPOSIT SECOND MASK
1316
PERFORM MATERIAL REMOVAL PROCESS
1318
DEPOSIT HARD MAGNETIC MATERIAL
1320
DEPOSIT ELECTRICALLY CONDUCTIVE LEAD MATERIAL

FIG 13